

01-09-02

Pocket No. 6333/TCG/TSM/LPCVD/LE

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

12/28/01


 jce79 U.S. PTO
 10/04/026
 12/28/01

 Patent Application
 Assistant Commissioner for Patents
 Washington, D.C. 20231
 Re:

 Inventor(s): Janardhanan Anand Subramony, Yoshitaka Yokota, Ramaseshan Suryanarayanan Iyer,
 Lee Luo, Aihua Chen

 Title: METHODS FOR SILICON OXIDE AND OXYNITRIDE DEPOSITION USING SINGLE WAFER LOW PRESSURE
 CVD

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 35 pages.
- ☒ Drawings totaling 15 pages, Formal ☒ Informal.
- ☒ Unsigned Declaration and Power of Attorney.

 Assignment of the invention to Applied Materials, Inc.
☒ Information Disclosure Statement (IDS)/PTO-1449 with copies of IDS citations.

☒ Check No. 47170 in the amount of \$1370.00

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	27	- 20 =	7	X \$18.00	126.00
Independent Claims	9	- 3 =	6	X \$84.00	504.00
Basic Filing Fee				\$740.00	\$740.00
TOTAL FEES					\$1370.00

 The Commissioner is hereby authorized to charge \$() to Deposit Account No. 50-1074.

☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 02-2666. A duplicate copy of this transmittal is enclosed.

☒ Please address all future correspondence to:

PATENT COUNSEL
 APPLIED MATERIALS, INC.
 Legal Affairs Department
 P.O. BOX 450A
 Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Box Patent Application, Assistant Commissioner for Patents, Washington, D.C. 20231.

Express Mail Receipt No. EL867648876US

Date of Deposit December 28, 2001

Signature

Michelle Beg

Respectfully submitted,

Michael A. Bernadicou

Michael A. Bernadicou
 Registration No. 35,934